



**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re application of: Wu et al.

Application No.: 10/789,103

Filed: February 27, 2004

Title: METHODS FOR PRODUCING LOW-  
K CDO FILMS WITH LOW RESIDUAL  
STRESS

Attorney Docket No.:  
NOVLP094/NVLS-2919

Examiner: Bret P. Chen

Group: 1762

**CERTIFICATE OF MAILING**

I hereby certify that this correspondence is being deposited with the U.S. Postal Service with sufficient postage as first-class mail on April 24, 2007 in an envelope addressed to the Commissioner for Patents, P.O. Box 1450 Alexandria, VA 22313-1450.

Signed: \_\_\_\_\_

Valerie Olsen

**AMENDMENT C**

Mail Stop Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

In response to the Office Action dated January 24, 2007 in the above-identified application, please consider the following:

**Remarks** beginning on page 2 of this paper.